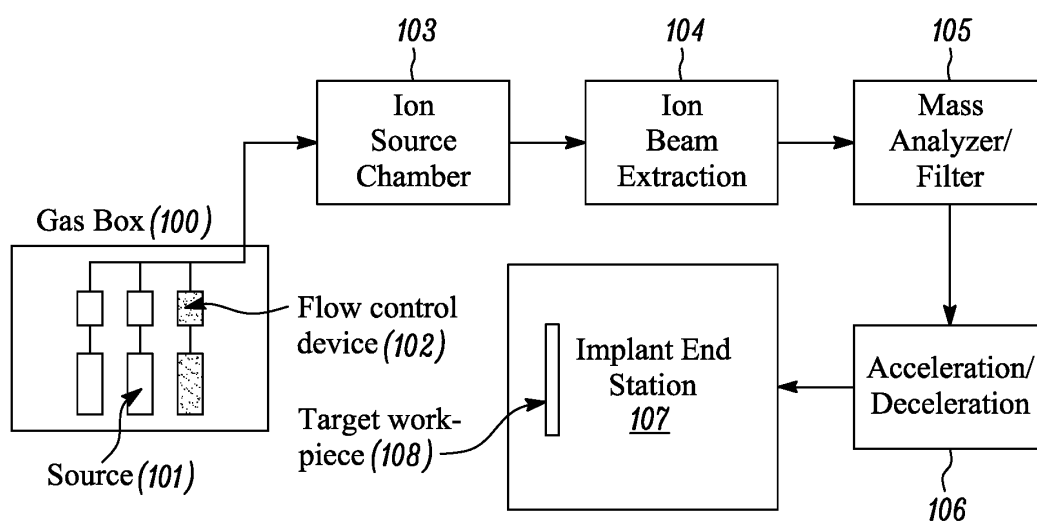
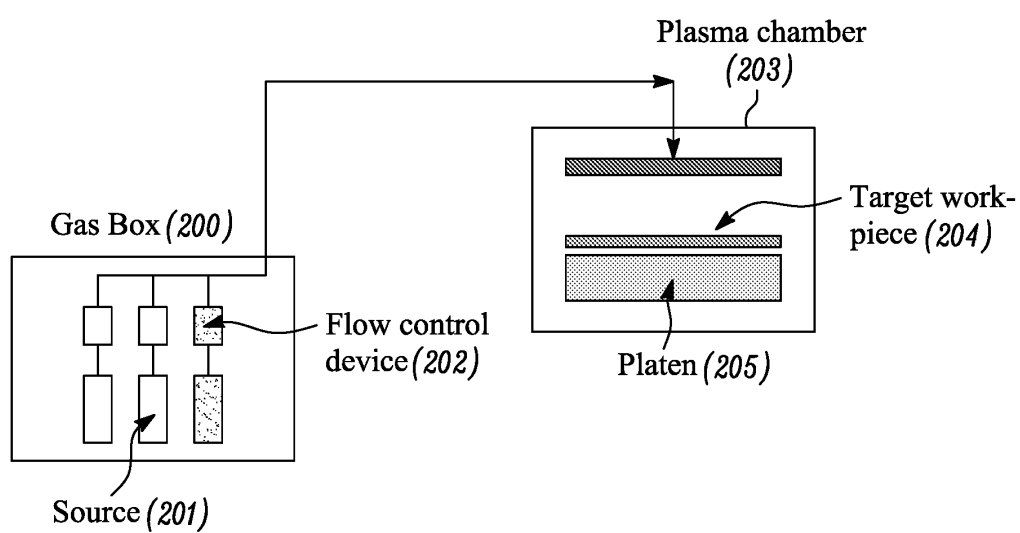




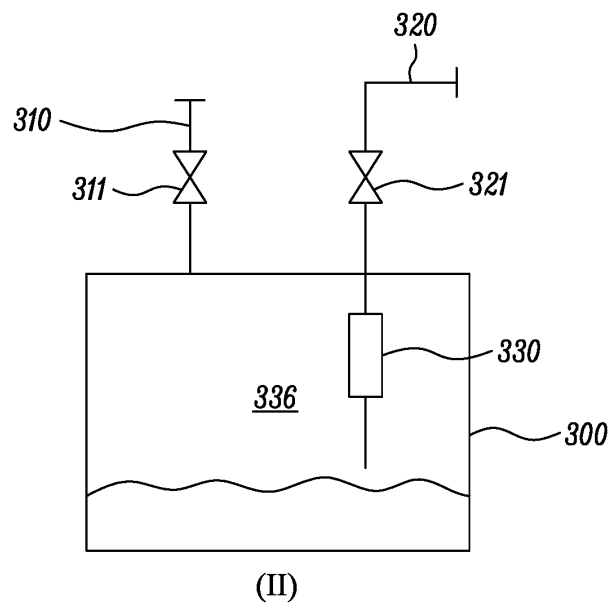
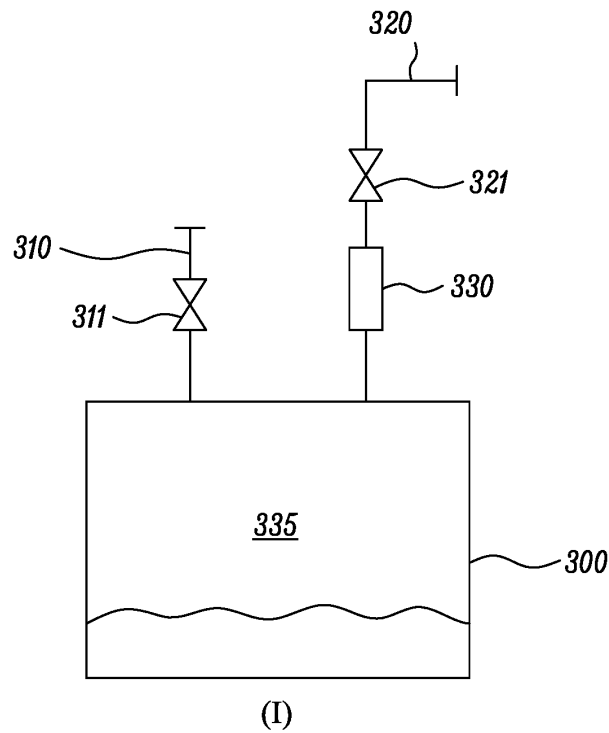
Schematic of beamline ion implant system

FIG. 1



Schematic of plasma immersion ion implant system

FIG. 2



PACKAGE FOR Sb CONTAINING DOPANT MATERIALS

FIG. 3

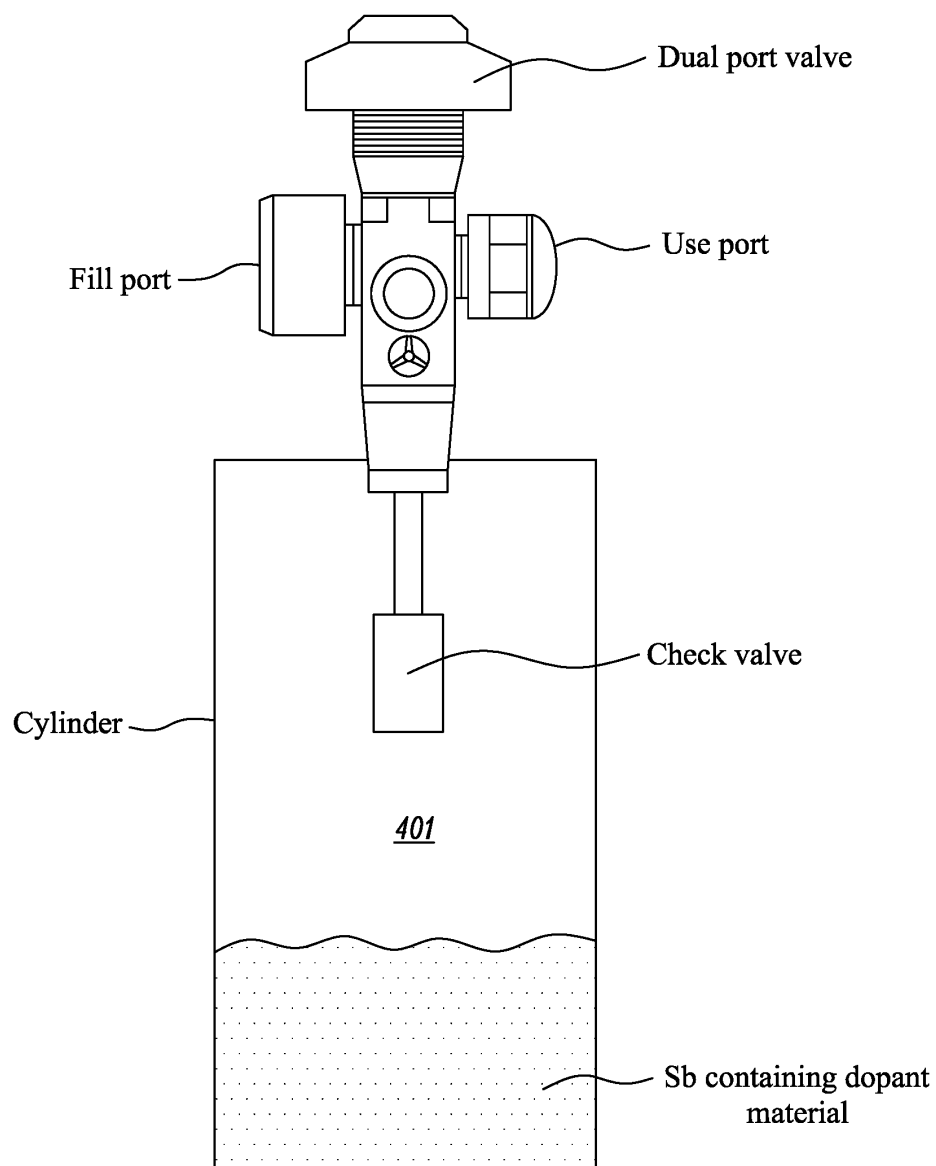


FIG. 4